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APPLICATION NO.	FILIN	G DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.
09/970,185	10/03/2001		Thomas Laursen	SFI 658C1	2268
27782	7590	07/31/2003			
		RPORATION	EXAMINER		
305 NORTH CHANDLER			ROSE, ROBERT A		
				ART UNIT	PAPER NUMBER
				3723	. /
				DATE MAILED: 07/31/2003	A

Please find below and/or attached an Office communication concerning this application or proceeding.

Application No. Office Action Summary

Applicant(s)

Examiner

09/970,185

Art Unit

Laursen et al

**Robert Rose** 

3723



The MAILING DA	TE of this communication appears	on the cover sheet with t	the correspondence address			
Period for Reply						
A SHORTENED STATUTORY PERIOD FOR REPLY IS SET TO EXPIRE <u>three</u> MONTH(S) FROM THE MAILING DATE OF THIS COMMUNICATION.						
•	e under the provisions of 37 CFR 1.136 (a). In a	no event, however, may a reply be	e timely filed after SIX (6) MONTHS from the			
	ve is less then thirty (30) days, a reply within th					
	bove, the maximum statutory period will apply a tended period for reply will, by statute, cause th	-				
<ul> <li>Any reply received by the Office la earned patent term adjustment. Se</li> </ul>	ter than three months after the mailing date of the 37 CFR 1.704(b).	nis communication, even if timely	filed, may reduce any			
Status						
1) Responsive to com	nmunication(s) filed on 10-3-01,	1-21-03	·			
2a) This action is <b>FINA</b>	AL. 2b) 💢 This act	on is non-final.				
	ion is in condition for allowance e ice with the practice under <i>Ex pai</i>	-	rs, prosecution as to the merits is 11; 453 O.G. 213.			
Disposition of Claims						
4) 💢 Claim(s) <u>1-28</u>			is/are pending in the application.			
4a) Of the above, cl	aim(s)		is/are withdrawn from consideration.			
5) Claim(s)			is/are allowed.			
6) X Claim(s) 1-25, 27,	and 28		is/are rejected.			
7) 💢 Claim(s) <u>26</u>			is/are objected to.			
8) 🗌 Claims		are subject	to restriction and/or election requirement.			
Application Papers						
9) The specification is	s objected to by the Examiner.					
10) ☐ The drawing(s) file	ed onis/are	a) accepted or b)	$\square$ objected to by the Examiner.			
Applicant may not	request that any objection to the d	rawing(s) be held in abey	vance. See 37 CFR 1.85(a).			
11) The proposed draw	ving correction filed on	is: a)□ a	pproved b) $\square$ disapproved by the Examiner.			
If approved, correc	cted drawings are required in reply t	o this Office action.				
12) The oath or declar	ation is objected to by the Exami	ner.				
Priority under 35 U.S.C. §	§ 119 and 120					
3) Acknowledgement is made of a claim for foreign priority under 35 U.S.C. § 119(a)-(d) or (f).						
a)□ All b)□ Some	e* c)□ None of:					
1. Certified cop	1. Certified copies of the priority documents have been received.					
2. Certified cop	2. Certified copies of the priority documents have been received in Application No					
applic	e certified copies of the priority do ation from the International Bure	au (PCT Rule 17.2(a)).	-			
*See the attached det	ailed Office action for a list of the	e certified copies not re	ceived.			
14) Acknowledgement	t is made of a claim for domestic	priority under 35 U.S.(	C. § 119(e).			
	of the foreign language provisiona					
15) ☐ Acknowledgement	t is made of a claim for domestic	priority under 35 U.S.(	C. §§ 120 and/or 121.			
Attachment(s)						
1) Notice of References Cited (PT		4) Interview Summary (PTO				
2) Notice of Draftsperson's Patent Drawing Review (PTO-948)  5) Notice of Informal Patent Application (PTO-152)  3) Information Disclosure Statement(s) (PTO-1449) Paper No(s). 2,3  6) Other:						
3/ IXI information Disclosure Stateme	яща) (F10-1443) Paper No(s)	o, Uther:				

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## **DETAILED ACTION**

1. Receipt is acknowledged of Applicant's prior Art Statements, filed October 3, 2001, and January 21, 2003, respectively.

- 2. Claims 1-28 are presented for examination.
- 3. The following is a quotation of the appropriate paragraphs of 35 U.S.C. 102 that form the basis for the rejections under this section made in this Office action:

A person shall be entitled to a patent unless -

- (b) the invention was patented or described in a printed publication in this or a foreign country or in public use or on sale in this country, more than one year prior to the date of application for patent in the United States.
- 4. Claims 1-5, 11-12, 14, and 16-24 are rejected under 35 U.S.C. 102(b) as being clearly anticipated by Sandhu et al(US 5700180). Sandhu et al disclose an apparatus for planarizing a front surface of a wafer comprising all of the subject matter set forth in applicant's claims above. Note the use of an interferometer(column 7, lines 35-45), which delivers reflected light signals back to a controller to adjust the polishing pressure on the backside of the wafer by way of plural individually controllable fluid-pressure piston actuators(column 6, lines 41-56). With regard to claim 14, note temperature probe embodiment of figure 10.
- 5. The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:
  - (a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negatived by the manner in which the invention was made.

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6. Claims 25, and 27-28 are rejected under 35 U.S.C. 103(a) as being unpatentable over Sandhu et al('180). It is known in the polishing art to employ an initial polishing run to determine various parameters with which to make subsequent polishing runs, in order to avoid too many rejected workpieces. To employ the method of Sandhu et al on successive wafers by utilizing data from a previous run to adjust the carrier plenum pressures for a subsequent run, in order to optimize the polishing parameters, would have been at most an obvious matter of design choice to those of ordinary skill in the art.

- 7. Claim 6 is rejected under 35 U.S.C. 103(a) as being unpatentable over Sandhu et al('180) in view of Brievogel et al(US 5554064). To substitute an orbital motion generator for the rotational motion generator disclosed in Sandhu et al in order to provide a more uniform polishing pad movement across the surface of the wafer(column 2, line 40 of Brievogel et al) would have been obvious in view of Brievogel et al.
- 8. Claims 7-9 are rejected under 35 U.S.C. 103(a) as being unpatentable over Sandhu et al('180) in view of Perlov et al(US 5964653). To utilize the pressure plenum/membrane arrangement disclosed in Perlov et al to alternatively deliver local pressure to a desired region of the wafer in the apparatus of Sandhu et al would have been obvious in view of Perlov et al.
- 9. Claim 10 is rejected under 35 U.S.C. 103(a) as being unpatentable over Sandhu et al in view of Perlov et al and further in view of Brievogel et al. To further substitute an orbital motion generator for the rotational motion generator disclosed in Sandhu et al in order to provide a more

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uniform polishing pad movement across the surface of the wafer(column 2, line 40 of Brievogel

et al) would have been obvious in view of Brievogel et al.

10. Claim 13 is rejected under 35 U.S.C. 103(a) as being unpatentable over Sandhu et

al('180) in view of Swedek et al(6190234). To use a second light source and detector for better

endpoint precision would have been obvious in view of Swedek et al.

11. Claim 15 is rejected under 35 U.S.C. 103(a) as being unpatentable over Sandhu et

al('180) in view of Li et al. Li et al discloses the conventional use of an eddy current sensor for

monitoring the polishing state of the workpiece. To substitute such a sensor for the optical

system of Sandhu et al to alternatively monitor the polishing state of the wafer would have been

obvious in view of Li et al.

12. Claim 26 is objected to as being dependent upon a rejected base claim, but would be

allowable if rewritten in independent form including all of the limitations of the base claim and

any intervening claims.

13. Any inquiry concerning this communication should be directed to Robert Rose at

telephone number (703) 308-1360.

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July 26, 2003.

ROBERT A. ROSE
PRIMARY EXAMINER
ART UNIT 323